Young Bong Shin

List of Publications by Year
in descending order

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17	129	1307594 7	1281871 11
papers	citations	h-index	g-index

17	17	17	97
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Influence of passivation layer on thermal stability of Nb:TiO2â^'x samples for shutter-less infrared image sensors. Infrared Physics and Technology, 2019, 100, 52-56.	2.9	3
2	Anodic Aluminum Oxide-Based IR Emitter for High-Speed Infrared Scene Projector. Journal of Microelectromechanical Systems, 2019, 28, 1032-1038.	2.5	7
3	Residual stress analysis of anodic aluminum oxide thin films for infrared emitter device application.. , 2019, , .		1
4	Enhanced bolometric properties of nickel oxide thin films for infrared image sensor applications by substitutional incorporation of Li. Ceramics International, 2018, 44, 7808-7813.	4.8	4
5	Influence of Nb Doping Concentration on Bolometric Properties of RF Magnetron Sputtered Nb:TiO2â^'x Films. Journal of Electronic Materials, 2018, 47, 2171-2176.	2.2	2
6	Improvement of the thermal stability of Nb:TiO_{2â^'x}samples for uncooled infrared detectors. Journal Physics D: Applied Physics, 2018, 51, 025104.	2.8	5
7	Bolometric properties of oxygen atmosphere annealed Nb:TiO 2â^'x films for infrared detectors. Ceramics International, 2017, 43, 9207-9213.	4.8	5
8	Sputtering pressure dependent bolometric properties of Ni 1â^'x O thin films for uncooled bolometer applications. Ceramics International, 2017, 43, 9498-9504.	4.8	4
9	Effect of sputtering pressure on microstructure and bolometric properties of Nb:TiO2â^'x films for infrared image sensor applications. Journal of Applied Physics, 2016, 119, .	2.5	12
10	Nb doping effect on TiO2â^'x films for bolometer applications. Journal of Physics and Chemistry of Solids, 2016, 91, 128-135.	4.0	9
11	Substrate temperature dependent bolometric properties of TiO2â^'x films for infrared image sensor applications. Ceramics International, 2016, 42, 17123-17127.	4.8	14
12	Influence of deposition temperature on TiO2â^'x films for infrared image sensor applications: TiO2â^'x films: Infrared image sensor applications. , 2015, , .		0
13	Bolometric properties of reactively sputtered TiO_{2â^'x}films for thermal infrared image sensors. Journal Physics D: Applied Physics, 2015, 48, 355104.	2.8	18
14	Oxygen partial pressure and thermal annealing dependent properties of RF magnetron sputtered TiO2â^'x films. Materials Science in Semiconductor Processing, 2015, 32, 107-116.	4.0	20
15	Enhanced bolometric properties of TiO2â^'x thin films by thermal annealing. Applied Physics Letters, 2015, 107, .	3.3	18
16	Systematic Investigation on Deposition Temperature Effect of Ni1â€“xO Thin Films for Uncooled Infrared Image Sensor Applications. IEEE Sensors Journal, 2015, 15, 7234-7241.	4.7	7
17	Oxygen Atmosphere Annealing Effect on the Thermal Stability of TiO_{2-x} Based Films for Shutter-Less Infrared Image Sensors. Key Engineering Materials, 0, 775, 272-277.	0.4	0